

FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
ASMEX.367AAPPLICATION NO.
10/074,534INFORMATION DISCLOSURE STATEMENT
BY APPLICANT

(USE SEVERAL SHEETS IF NECESSARY)

APPLICANT
Michael A. ToddFILING DATE
February 11, 2002GROUP
2812

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
	6,159,828	12/12/00	Ping et al.	438	486	
	6,171,662 B1	01/09/01	Nakao	427	595	
	6,197,669 B1	03/06/01	Twu et al.	438	585	

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

EXAMINER INITIAL	

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EXAMINER	DUPLICATE - ORIGINAL	DATE CONSIDERED	INITIALED ON 6/31/03
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.			

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U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
SN	1	V. Z-Q Li <i>et al.</i> , Appl. Phys. Lett. 71(23) 3388-90 (1997)
	2	T-J King <i>et al.</i> , J. Electrochem. Soc., 141(8) 2235-41 (1994)
	3	A. Kovalgin <i>et al.</i> , ProRISC/IEEE 311-17 (1998)
	4	C. Hernandez <i>et al.</i> , Mat. Res. Soc. Symp. Proc. 533 93-98 (1998)
	5	M. Cao <i>et al.</i> , J. Electrochem. Soc., 142(5) 1566-72 (1995)
SN	6	J. Holleman <i>et al.</i> , J. Electrochem. Soc. 140(6) 1717-22 (1993)

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EXAMINER	DATE CONSIDERED
9	9/27/2004

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		FILING DATE February 11, 2002	GROUP 2814

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
1. <i>gh</i>	5,214,002	05/25/93	Hayashi et al.			
2. <i>gh</i>	5,356,821	10/18/94	Naruse et al.			
3. <i>gh</i>	5,471,330	11/28/95	Sarma			
4. <i>gh</i>	6,103,600	08/15/00	Ueda et al.			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
5. <i>gh</i>	11317530	16-11-99	Japan (abstract)			X	
6. <i>gh</i>	EP 0368651 A2	16-05-90					
7. <i>gh</i>	EP 0486047 A2	20-05-92					
8. <i>gh</i>	EP 0747974 A2	11-12-96					
9. <i>gh</i>	EP 1065728 A2	03-01-01					
10. <i>gh</i>	GB 2332564 A	23-06-99	United Kingdom				

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)
<i>gh</i>	Olivares, J. et al.; "Solid-phase crystallization of amorphous SiGe films deposited by LPCVD on SiO ₂ and glass," Thin Solid Films 337 (1999) pp. 51-54.

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EXAMINER <i>gh</i>	DATE CONSIDERED <i>9/27/2004</i>
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SL	1.	5,389,398	02/14/95	Suzuki et al.	427	130	
	2.	5,698,771	12/16/97	Shields et al.	73	31.05	
	3.	6,228,181	05/08/01	Yamamoto et al.	148	33.5	
	4.	6,326,311	12/04/01	Ueda et al.	438	694	
	5.	6,455,892	09/24/02	Okuno et al.	257	328	
SL	6.	6,613,695	09/02/03	Pomarede et al.	438	767	

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							YES	NO

EXAMINER
INITIAL

OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

SL	7.	Ikoma et al., Growth of Si/3C-SiC/Si(100) heterostructures by pulsed supersonic free jets, Applied Physics Letters, Volume 75, No. 25, Pp. 3977-3979, December 1999					

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EXAMINER	9	DATE CONSIDERED	9/27/2004
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